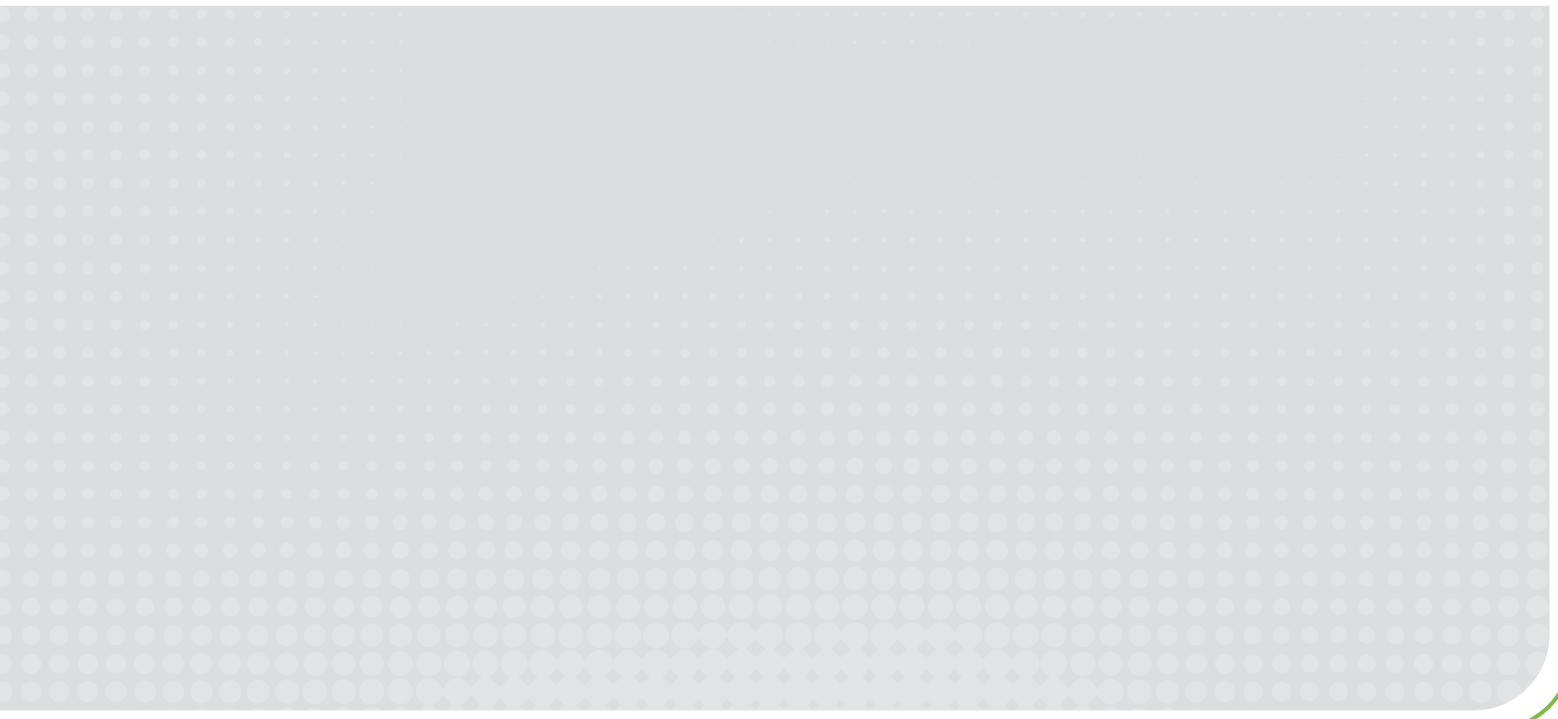
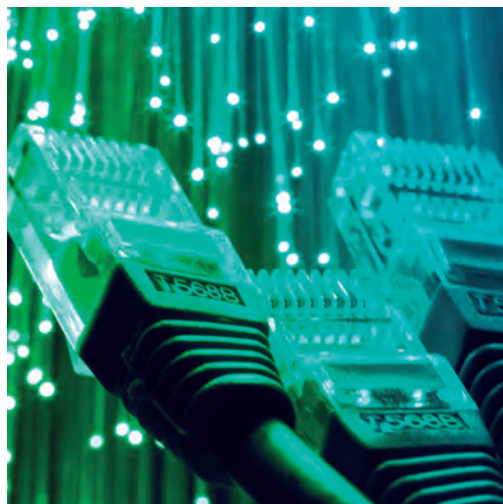


# ETHERCAT® PRODUCT SELECTION GUIDE

NEW STANDARDS IN PERFORMANCE & FLEXIBILITY



**AUTOMATION & CONTROL**



ETG.5003.1

**PAC 100**  
Programmable Automation Controller

- Modular, scalable, and configurable programmable control solution
- Supports standard IEC 61131-3 environment
- Seamless interface with HMI, supporting OPC UA



ETG.5003.2060

**MultiTherm™ 2000**  
Modular Temperature Controller

- Easily configured for single zone or multi-zone temperature control (48+)
- Ideal for dynamic control applications requiring tight temperature stability
- Precision sensor input channels, accepting RTDs, all thermocouple types, voltage and current inputs



ETG.5003.1

**CM**  
Communication Fieldbus Coupler Module

- Compact, customizable solution for standalone manual control, data logging, or distributed I/O, or EtherCAT gateway
- Scalable to any number of MKS I/O slices to create a distributed I/O support for up to hundreds of I/O channels



ETG.5003.1

**Analog IO**  
Analog Input/Output Module

- Compact and high density solution for a variety of input and output ranges
- Each AIO module supports 8 analog inputs and 4 analog outputs
- Supporting voltage inputs and outputs are configurable: 0-5V, 0-10V, ±5V, ±10V, 0-20mA, 4-20mA (ranges)

**AUTOMATION & CONTROL**



ETG.5003.1

**Digital IO**  
Digital Input/Output Module

- Integrates digital input and output channels with MKS PAC or CM modules
- Each DIO module supports 12 digital inputs and outputs



ETG.5003.1

**MicroNode™ Combo**  
Programmable Automation Controller

- Each MicroNode module supports 16 DIO
- Each module supports 16-bit, 8 analog inputs, 4 analog outputs, ±10V



ETG.5003.1

**HyperPAC**  
Programmable Industrial PC

- Ease of fieldbus protocols integration with IIoT solution
- Compact form factor
- Robust IPC
- Flexible configuration

## FLOW/GAS DELIVERY



ETG.5003.2020



ETG.5003.2025



ETG.5003.2025



ETG.5003.2025

### G Series

#### Mass Flow Controllers and Meters

- Full Scale flow rates from 5 sccm to 300 slm
- Proven, patented thermal sensor and mechanical design
- Multi-range/multi-gas capability; 1% of set point accuracy

### G Series

#### Pressure Controllers

- Pressure control for Full Scale from 500 Torr to 100 psia
- Thermally stable pressure sensor for 1% of set point accuracy
- Digital flow control algorithm for fast response to set point

### P Series

#### Pressure Controllers

- Pressure control for Full Scale from 10 to 1000 Torr
- Thermally stable pressure sensor for 1% of set point accuracy
- Flow meter option for backside wafer pressure control applications

### P Series

#### Dual Zone Pressure Controller

- Pressure control for Full Scale for 20, 50 or 100 Torr
- Integrated mass flow meter
- Full Scale flow measurement range for 20, 50, 100 sccm

## FLOW/GAS DELIVERY



ETG: MKS Specific

### Delta™

#### Flow Ratio Controllers

- Accurate and repeatable flow ratio control for better process optimization
- For use in cascade configurations
- Operates to temperatures up to 60°C ambient

### HA-MFV

#### High Accuracy In-Situ Mass Flow Verifier

- Flow rates up to 3000 sccm
- External volume insensitivity
- Reading measurement accuracy of 1.0% or better

PLASMA SOURCES



ETG.5003.201X



ETG.5003.201X



ETG.5003.201X



ETG.5003.201X

**Paragon®**

**Remote Plasma Sources**

- For high gas dissociation rates (>98%) of NF<sub>3</sub>
- Gas flows up to 8 slm and pressures up to 10 Torr
- Compatible with O<sub>2</sub> and NF<sub>3</sub> mixed gases

**R\*evolution®**

**Remote Plasma Sources**

- Up to 6kW of plasma power
- Integrated, self-contained unit for on-chamber installation
- Quartz plasma applicator, high density for oxygen species

**CM12P1**

**Remote Plasma Source**

- 12kW of plasma power
- Compatible with NF<sub>3</sub>, O<sub>2</sub>, N<sub>2</sub>, and Ar
- Meets Semi F47 immunity response requirements

**CH24P1**

**Remote Plasma Source**

- 24kW of plasma power
- Supports high flow applications
- Split power train for flexible installation

PRESSURE/VACUUM MEASUREMENT



ETG.5003.2080



ETG.5003.2080



ETG.5003.2080



ETG.5003.2080

**901P**

**Load Lock Transducer**

- Designed specifically for semiconductor load lock applications
- Providing medium vacuum measurement and atmospheric switching
- Fast and accurate pressure measurement for improved cycle time and particle reduction

**902B**

**Vacuum Transducer**

- 1000 Torr Full Scale range
- Piezo resistive diaphragm sensor
- Stainless steel diaphragm

**925 MicroPirani™**

**Vacuum Transducer**

- MEMS-based technologies, including MicroPirani™ technology
- Applicable for foreline and general vacuum measurement applications
- Fast and accurate pressure measurement

**972B DualMag™**

**Cold Cathode Transducer**

- Single transducer with wide pressure measurement range from atmosphere to ultra-high vacuum
- MEMS-based MicroPirani technology combined with cold cathode ionization technology
- Small footprint design

## PRESSURE/VACUUM MEASUREMENT



ETG.5003.2080



ETG.5003.2080



ETG.5003.2080



ETG.5003.2080

### DA02B

#### Baratron® Capacitance Manometer

- Unheated or temperature-controlled at 45°C, 80°C, 100°C
- Industry-leading accuracy and repeatability
- Inconel®-based sensor offers superior corrosion resistance to common process gases

### DA03B

#### Baratron® Capacitance Manometer

- High temperature-controlled at 150°C to 200°C
- Optional internally-mounted solid state process relays
- Compact design

### DA05A

#### Baratron® Capacitance Manometer

- Ambient operating temperature at 60°C
- 0.1 - 1.0 Torr Full Scale ranges
- Standard sensor or etch/fluorine/deposition-friendly sensor option

### DA06A

#### Baratron® Capacitance Manometer

- Temperature-controlled at 45°C, 80°C, 100°C
- 1 Torr and 1000 Torr Full Scale ranges
- Standard sensor or fluorine/deposition-friendly sensor option

## PRESSURE/VACUUM MEASUREMENT



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ETG.5003.2080

### 390 Micro-Ion®

#### Vacuum Transducer

- Combined Micro-Ion® ionization gauge technology, Conductron heat loss sensor, and 2 Piezo resistive sensors
- Continuous pressure measurement from high vacuum to atmosphere

### 392 Micro-Ion®

#### Vacuum Transducer

- Combined Micro-Ion® ionization gauge technology with a miniature Pirani Conductron heat-loss sensor
- Dual ionization gauge filaments



### SENSING SOLUTIONS



ETG.5003.1

### VALVES



ETG.5003.2030

### TEMPERATURE CONVERTER

#### Multichannel

- 3 – 5 channels
- $\pm 0.1^{\circ}\text{C}$  ( $2\sigma$ ) stability
- $0.01^{\circ}\text{C}$  resolution

### T2BA

#### Exhaust Throttle Valve

- Advanced model-based pressure control algorithm
- High-speed configurations available (<250 msec. open to close)
- Selectable high torque drives with soft-sealing available

Product	Mailbox Service	Synchronization	Firmware
<b>Automation &amp; Control</b>			
PAC Programmable Automation Controller MultiTherm™ Modular Temperature Controller CM Communication Fieldbus Coupler Module	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	<ul style="list-style-type: none"> <li>• Free Run (to loop update)</li> <li>• DC Event</li> <li>• SM Event</li> </ul>	Yes
Analog IO Analog Input/Output Module MicroNode™ Combo Programmable Automation Controller HyperPAC Programmable Industrial PC	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	<ul style="list-style-type: none"> <li>• Free Run</li> <li>• DC Event</li> <li>• SM Event to 500 usec</li> </ul>	Yes
Digital IO Digital Input/Output Module	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	<ul style="list-style-type: none"> <li>• Free Run</li> <li>• DC Event</li> <li>• SM Event to 200 usec</li> </ul>	Yes
<b>Flow</b>			
G Series Mass Flow Controllers & Meters G Series Pressure Controllers	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	<ul style="list-style-type: none"> <li>• Free Run</li> <li>• SM2</li> </ul>	Yes
P Series Pressure Controllers P Series Dual Zone Pressure Controllers Delta™ Flow Ratio Controllers	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	<ul style="list-style-type: none"> <li>• Free Run</li> <li>• SM2</li> </ul>	Via FoE
HA-MFV Insitu Mass Flow Verifier	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	<ul style="list-style-type: none"> <li>• Free Run</li> <li>• SM3</li> </ul>	Via FoE
<b>Pressure/Vacuum Measurement</b>			
901P Load Lock Transducer 902B Vacuum Transducer 925 MicroPirani Vacuum Transducer 972B DualMag™ Cold Cathode Transducer 390 Micro-Ion® Vacuum Transducer 392 Micro-Ion® Vacuum Transducer	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	SM Event	<ul style="list-style-type: none"> <li>• EtherCAT</li> <li>• Transducer</li> </ul>
DA02B Baratron® Capacitance Manometer DA03B Baratron® Capacitance Manometer DA05A Baratron® Capacitance Manometer DA06A Baratron® Capacitance Manometer	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	Free Run	Yes
<b>Sensing Solution</b>			
Temperature Converter	CoE	Free Run	EtherCAT
<b>Valves</b>			
T2BA Exhaust Throttle Valve	<ul style="list-style-type: none"> <li>• CoE</li> <li>• FoE</li> </ul>	<ul style="list-style-type: none"> <li>• Free Run (to loop update)</li> <li>• DC Event</li> <li>• SM Event</li> </ul>	<ul style="list-style-type: none"> <li>• Via FoE</li> <li>• Via Web GUI</li> </ul>

Product	Synchronization	Monitor Parameters
<b>Plasma Sources</b>		
Paragon® Remote Plasma Sources Revolution® Remote Plasma Sources CM12P1 Remote Plasma Source CH24P1 Remote Plasma Source	Free Run	<ul style="list-style-type: none"> <li>• Power</li> <li>• Run Time / Ignition Time</li> <li>• Faults</li> <li>• AC/DC Line</li> <li>• System Ready</li> <li>• Internal Device Temperature</li> </ul>

## WHY MKS?

### CRITICAL TECHNOLOGIES

World-class technology and development capabilities for leading-edge processes



### PROVEN PARTNER

Recognized leader delivering innovative, reliable solutions for our customers' most complex problems



### OPERATIONAL EXCELLENCE

Consistent execution across all aspects of our business



### COMPREHENSIVE PORTFOLIO

Extensive offering of products and services for the markets we serve



**MKS INSTRUMENTS** enables technologies that transform our world. We deliver foundational technology solutions to leading edge semiconductor manufacturing, electronics and packaging, and specialty industrial applications.

We apply our broad science and engineering capabilities to create instruments, subsystems, systems, process control solutions and specialty chemicals technology that improve process performance, optimize productivity and enable unique innovations for many of the world's leading technology and industrial companies.

Our solutions are critical to addressing the challenges of miniaturization and complexity in advanced device manufacturing by enabling increased power, speed, feature enhancement, and optimized connectivity. Our solutions are also critical to addressing ever-increasing performance requirements across a wide array of specialty industrial applications.

Additional information can be found at [www.MKS.com](http://www.MKS.com).

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